

FORM PTO-1449 (Modified)	ATTY. DOCKET NO. FIS920030185US1	SERIAL NO. 10/605/167
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT		
(Use several sheets if necessary)	FILING DATE: 9/12/03	GROUP: 2822

JUN 28 2004
U.S. PATENT & TRADEMARK OFFICE
CJC

REFERENCE DESIGNATION		U.S. PATENT DOCUMENTS				
EXAMINER INITIALS	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPRO.)
REB	6,228,694 B1	5/8/2001	Doyle et al.			
REB	6,406,973 B1	6/18/2002	Lee			
REB	6,281,532 B1	8/28/2001	Doyle et al.			
REB	5,683,934	11/4/97	Candelaria			
REB	6,368,931 B1	4/9/2002	Kuhn, et al.			
REB	5,310,446	5/10/94	Konishi et al.			
REB	4,853,076	8/1/89	Tsaur et al.			
REB	US 2002/0090791 A1	7/11/2002	Doyle et al.			
REB	US 2002/0074598 A1	6/20/2002	Doyle et al.			
REB	6,509,618 B2	7/21/2003	Jan et al.			
REB	6,476,462 B2	11/5/2002	Shimizu et al.			
REB	6,362,082 B1	3/26/2002	Doyle et al.			
REB	6,228,694 B1	5/8/2001	Doyle et al.			
REB	5,565,697	10/15/96	Asakawa et al.			
REB	US 2003/0040158 A1	2/27/2003	Saitoh			
REB	US 2002/0086472 A1	7/4/2002	Roberds et al.			
REB	6,521,964 B1	2/18/2003	Jan et al.			
REB	6,506,652	01/14/03	Jan, et al.			

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)

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EXAMINER	DATE CONSIDERED
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LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT		APPLICANT: Dureseti Chidambarrao, et al.	
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REFERENCE DESIGNATION		U.S. PATENT DOCUMENTS				
EXAMINER INITIALS	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPRO.)
KSP	5,081,513	1/14/1992	Jackson, et al.			
KSP	3,602,841	8/31/1971	McGroddy			
KSP	6,531,740	3/11/2003	Bosco, et al.			
KSP	6,531,369	3/11/2003	Ozkan, et al.			
KSP	6,501,121	12/31/2002	Yu, et al.			
KSP	6,498,358	12/24/2002	Lach, et al.			
KSP	6,493,497	12/10/2002	Ramdani, et al.			
KSP	6,403,975	6/11/2002	Brunner, et al.			
KSP	6,361,885	3/26/2002	Chou			
KSP	6,255,169	7/3/2001	Li, et al.			
KSP	6,246,095	6/12/2001	Brady, et al.			
KSP	6,165,383	12/26/2000	Chou			
KSP	6,133,071	10/17/2000	Nagai			
KSP	6,046,464	4/4/2000	Schetzina			
KSP	6,025,280	2/15/2000	Brady, et al.			

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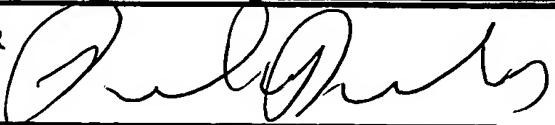
REFERENCE DESIGNATION		U.S. PATENT DOCUMENTS				
EXAMINER INITIALS	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPRO.)
REP	5,940,736	8/17/1999	Brady, et al.			
REP	5,880,040	3/9/1999	Sun, et al.			
REP	5,861,651	1/19/1999	Brasen, et al.			
REP	5,679,965	10/21/1997	Schetzina			
REP	5,670,798	9/23/1997	Schetzina			
REP	5,561,302	10/1/1996	Candelaria			
REP	5,471,948	12/5/1995	Burroughes, et al.			
REP	5,459,346	10/17/1995	Asakawa, et al.			
REP	5,391,510	2/21/1995	Hsu, et al.			
REP	5,371,399	12/6/1994	Burroughes, et al.			
REP	5,108,843	4/28/1992	Ohtaka, et al.			
REP	5,060,030	10/22/1991	Hoke			
REP	4,958,213	9/18/1990	Eklund, et al.			
REP	4,665,415	5/12/1987	Esaki, et al.			

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REFERENCE DESIGNATION		U.S. PATENT DOCUMENTS		
EXAMINER INITIALS	DOCUMENT NUMBER	DATE	NAME	CLASS
XEP	5,989,978	11/23/1999	Peidous	
XEP	6,284,626	9/4/2001	Kim	
XEP	6,274,444	8/14/2001	Wang	
XEP	6,261,964	7/17/2001	Wu, et al.	
XEP	6,221,735	4/24/2001	Manley, et al.	
XEP	6,117,722	9/12/2000	Wuu, et al.	
XEP	6,107,143	8/22/2000	Park, et al.	
XEP	6,090,684	7/18/2000	Ishitsuka, et al.	
XEP	6,066,545	5/23/2000	Doshi, et al.	
XEP	6,008,126	12/28/1999	Leedy	
XEP	5,946,559	8/31/1999	Leedy	
XEP	5,840,593	11/24/1998	Leedy	
XEP	5,592,018	1/7/1997	Leedy	
XEP	5,592,007	1/7/1997	Leedy	
XEP	5,571,741	11/5/1996	Leedy	

FOREIGN PATENT DOCUMENTS		TRANSLATION					
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EXAMINER		DATE CONSIDERED	10/16/04
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FORM PTO-1449 (Modified)	ATTY. DOCKET NO. FIS92003018SUS1	SERIAL NO. 10/605,167
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REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

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EXAMINER	<i>John Shultz</i>	DATE CONSIDERED	10/14/84
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Form PTO-1449 (Modified)	Attorney Docket No.: <u>FIS920030 185</u>	Serial No.: <u>10/605,167</u>
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT		1 P E JUN 28 2004 FEE PAID PCP 95
(Use several sheets if necessary)	Page 1 of 1	Filing Date: <u>9/12/03</u>

REFERENCE DESIGNATION		U.S. PATENT DOCUMENTS				
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<i>REB</i>	Kem Rim, et al., "Transconductance Enhancement in Deep Submicron Strained-Si <i>n</i> -MOSFETs", International Electron Devices Meeting, 26, 8, 1, IEEE, September 1998.
<i>REB</i>	Kem Rim, et al., "Characteristics and Device Design of Sub-100 nm Strained Si N- and PMOSFETs", 2002 Symposium On VLSI Technology Digest of Technical Papers, IEEE, pp 98-99.
<i>REB</i>	Gregory Scott, et al., "NMOS Drive Current Reduction Caused by Transistor Layout and Trench Isolation Induced Stress", International Electron Devices Meeting, 34.4.1, IEEE, September 1999.
<i>REB</i>	F. Ootsuka, et al., "A Highly Dense, High-Performance 130nm node CMOS Technology for Large Scale System-on-a-Chip Application", International Electron Devices Meeting, 23.5.1, IEEE, April 2000.
<i>REB</i>	Shinya Ito, et al., "Mechanical Stress Effect of Etch-Stop Nitride and its Impact on Deep Submicron Transistor Design", International Electron Devices Meeting, 10.7.1, IEEE, April 2000.
<i>REB</i>	A. Shimizu, et al., "Local Mechanical-Stress Control (LMC): A New Technique for CMOS-Performance Enhancement", International Electron Devices Meeting, IEEE, March 2001.
<i>REB</i>	K. Ota, et al., "Novel Locally Strained Channel Technique for high Performance 55nm CMOS", International Electron Devices Meeting, 2.2.1, IEEE, February 2002.

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